

Resource Summary Report

Generated by [NIF](#) on Sep 22, 2026

FEI: OptiFIB Taipan for Semiconductors

RRID:SCR_019895

Type: Tool

Proper Citation

FEI: OptiFIB Taipan for Semiconductors (RRID:SCR_019895)

Resource Information

URL: <https://www.fei.com/products/fib/optifib-taipan-for-semiconductors/>

Proper Citation: FEI: OptiFIB Taipan for Semiconductors (RRID:SCR_019895)

Description: Focused ion beam system that for semiconductors that enables a highly controlled beam profile and current, accurate navigation and ion beam placement, and reliable end-pointing.

Resource Type: instrument resource

Keywords: FEI, FIB Microscope, Instrument Equipment, USEdit,

Availability: Commercially available

Resource Name: FEI: OptiFIB Taipan for Semiconductors

Resource ID: SCR_019895

Alternate IDs: Model_Number_OptiFIB

Record Creation Time: 20220129T080347+0000

Record Last Update: 20260919T195421+0000

Ratings and Alerts

No rating or validation information has been found for FEI: OptiFIB Taipan for Semiconductors.

No alerts have been found for FEI: OptiFIB Taipan for Semiconductors.

Data and Source Information

Source: [SciCrunch Registry](#)

Usage and Citation Metrics

We have not found any literature mentions for this resource.